## MATION DISCLOSURE **CITATION**

US PATENT DO	CUMENTS
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AND MATION DISCLOSURE CITATION		ATTORNEY'S DOCKET NO.: 99-34R1		ICATION NO.: 01,858	SCONDO SONO	
	PTO-1449		APPLICANT:	L	A,	, CX
			Hagemeyer et al.		<b>一</b>	52074
		FILING DATE: 7/9/2001	GRC 1764	OUP:	200	
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EQ.	DE 198 09 477 A1	9/16/99	Germany	G01N	31/10	x	
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AUG 1 9 2002 ATTORNEY'S DOCKET NO .: APPLICATION NO.: HEORNA TION DISCLOSURE TC 1700 99-34R1 09/901,858 CITATION PTO-1449 APPLICANT: Hagemeyer et al. FILING DATE: GROUP: 7/9/2001 1764 **FOREIGN DOCUMENTS EXAMINER'S** PATENT NO. DATE COUNTRY CLASS SUB TRANSLATION INITIALS CLASS YES NO WO 97/32208 9/04/97 PCT **G01N** 31/10 WO 98/03521 1/29/98 PCT C07F 19/00 WO 98/07026 2/19/98 PCT **G01N** 31/10 х WO 98/13137 4/02/98 PCT B01J 19/00 X WO 98/13605 4/02/98 PCT F15C 5/00 х WO 98/53236 11/26/98 PCT F16K 31/126 х WO 99/41005 8/19/99 PCT B01J 19/00 X WO 00/09255 EUR 2/24/00 PCT B01J 19/00 WO 00/14529 3/16/00 PCT G01N 31/02 KQ WO 00/17413 3/30/00 PCT C23C 14/04 PU WO 00/51720 9/08/00 PCT B01J 19/00 X WO 01/00315 1/04/01 1/0 PCT B01J 19/00 х WO 01/66245 9/13/01 PCT **B01J** 19/00 OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages etc.) Berenschot, J.W., et al., "Micromachining of {111} Plates in <001> Oriented Silicon", J. Micromech. Microeng. 8 (1998) 104-107 Bruns, Mark W., "The Application of Silicon Micromachining Technology and High Speed Gas Chromatography to On-Line Process Control", MTI Analytical Instruments Bruns, Mark W., "Silicon Micromachining and High Speed Gas Chromatography", IEEE, 1992, pp. 110 1640-1644 w Grosjean et al., "A Practical Thermopneumatic Valve", IEEE, 1999, pp. 147-152 ED Haswell, Stephen J. et al., "The Application of Micro Reactors to Synthetic Chemistry", Chem. Commun., 2001, 391-398 Hendrix, Charles D., "What Every Technologist Should Know About Experimental Design", Chemtech, #W 1979, pp. 167-174 Henning, Albert K. et al., "Microfluidic MEMS for Semiconductor Processing", IEEE, 1998, Vol. 21, W pp. 329-337

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